

SUBSTRATE STORAGE CONTAINER

Abstract

To provide a substrate storage container which prevents air and others from penetrating into the container body and contaminating the substrates by suitably sealing between the container body and the door element.

A container includes: a container body 1 for storing substrates of semiconductor wafers; a door element 20 to be detachably fitted to an open front portion 7 of container body 1; and a compressively deformable gasket 30 for sealing between container body 1 and door element 20. While a sealing surface 11 for gasket 30 is formed on the inner periphery of open front portion 7 of container body 1 so that the difference between the maximum and the minimum of the flatness is specified to be less than 0.50 mm, a fitting portion 22 for gasket 30 is formed in a frame shape. Gasket 30 is formed of a base 31 to be fitted to fitting portion 22; a flexible sealing part 34 extended from base 31 toward sealing surface 11; and a contact portion 36 that is curvedly formed at the distal end of sealing part 34 and put in press-contact with sealing surface 11.

Figure 6